Appl. No. 10/519,175 Amdt. dated May 9, 2008 Amendment under 37 CFR 1.116 Expedited Procedure Examining Group 2813

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1-17. (canceled)

1 18. (previously presented) A method as in claim 24 wherein step (b) advances 2 curing of the thermosetting resin.

19 and 20. (canceled)

- 1 21. (previously presented) A method as in claim 24 wherein the semiconductor device comprises an integrated circuit.
- 1 22. (previously presented) A method as in claim 24 wherein step (a) includes a transfer molding process.
- 1 23. (previously presented) A method as in claim 24 wherein step (a) includes a potting process.
- 1 24. (previously presented) A method of making a semiconductor device
- 2 comprising:
- 3 (a) sealing the semiconductor device in a package by surrounding it with
- 4 thermosetting resin and thermally curing the resin at a first temperature;
- 5 (b) baking the thermosetting resin at a second temperature not higher than the 6 first temperature;
- 7 (c) further baking the thermosetting resin at a third temperature higher than
- 8 the first temperature, wherein the third temperature is between about 220°C and about 260°C;
- 9 and

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10	(d)	inspecting the semiconductor device.
1	25.	(previously presented) A method as in claim 24 wherein a conductive lead
2	is adhesively affixed	to a main surface of the semiconductor device.
1	26.	(previously presented) A method as in claim 25 wherein the conductive
2	lead is adhesively aff	ixed to a peripheral portion of the main surface of the semiconductor
3	device.	
1	27.	(previously presented) A method as in claim 26 wherein an electrode of
2	the semiconductor de	evice is electrically connected to the conductive lead.
	28-30	(canceled)